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1 Selective electric field assisted dissolution as a technique for micro 2 and nano structuring of metal thin films

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6 A technique for patterning compact thin metal layers is presented. The technique is based on a
7 successive application of well known, cost-effective, and simple methods of glass poling and elec-
8 tric field assisted dissolution. A microstructure from the patterned anode was copied onto a thin sil-
9 ver layer on a glass substrate. It is demonstrated that electric field assisted dissolution can be used
10 for selective dissolution of compact metal layers. Nanostructuring of compact metal layers is inter-
11 esting as it can be used in the production of metamaterials, metasurfaces, and optical circuits. The
12 proposed two-step technique does not involve expensive equipment, and the duration of the struc-
13 turing process is independent of the size of the required structured surface. *Published by AIP
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14 Micro- and nano-structured conductive layers are fabri-
15 cated using engraving techniques, photolithography, X-ray
16 lithography, or electron beam lithography, depending on the
17 required scale of the structure.¹⁻⁴ Some of these techniques
18 involve expensive equipment. Moreover, the structuring pro-
19 cess may be time-consuming, especially in the case when a
20 large area with a high resolution structure is demanded. In
21 this paper, we demonstrate an alternative technique for con-
22 ductive layer patterning, based on the processes of thermal
23 glass poling⁵ and electric field assisted dissolution (EFAD)
24 of metal.⁶⁻⁸

25 In the process of glass poling, an internal electric field
26 forms in the glass upon application of an external electric
27 field and increased temperature.⁹ Alkali ions contained in the
28 glass are driven by an external electric field and drift towards
29 the cathode. Na⁺ ions, having the highest mobility, domi-
30 nantly contribute to the ionic current. The mobility of ions
31 increases with the rise in temperature. As a result, the region
32 below the cathode is depleted by ions and the internal elec-
33 tric field is formed due to the ion redistribution. The region
34 remains depleted even after turning off the external electric
35 field and cooling. It is possible to obtain a selective depletion
36 in the glass structure by applying a patterned anode: the
37 depletion occurs only in the regions beneath the contacts
38 with the electrode. Since the depleted regions have a lower
39 molar volume, poling with the patterned anode also results in
40 the relief structuring of the glass surface itself.^{5,10}

41 Similar to glass poling, the EFAD process involves the
42 application of an external electric field and increased temper-
43 ature. Upon application of the external electric field to a
44 glass containing metal nanoparticles, the electrons from
45 metal atoms embedded in the glass matrix are stripped away
46 and metal ions start drifting, similar to alkali ions.⁷ The
47 application of a patterned anode to a metal island film
48 (MIF)¹¹ results in the patterning of the film: metal nanopar-
49 ticles beneath the anode contacts are dissolved, but else-
50 where they remain on the glass surface. In fact, EFAD and
51 glass poling in this case take place simultaneously. Besides

the process of metal nanoparticle dissolving, the glass sur-
face region beneath the anode depletes with Na⁺ ions, result-
ing in a patterned surface if a structured anode is applied.¹²

EFAD enables the dissolution of metal nanoparticles
embedded in a glass matrix, located on a glass surface as a
MIF, embedded in a thin dielectric film,¹³ or from a compact
metal thin film.¹⁴ However, all the attempts to make a selec-
tive EFAD of a compact metal thin film thus far were unsuc-
cessful. The problem is that even if the contact with the
anode is realized in only one point, the whole metal layer
sets at the same potential and the dissolution unselectively
starts throughout the whole layer. At this point, it is impor-
tant to highlight that compact metal layers are of special
interest for nano- and micro-structuring, as they could be
used for metamaterials, metasurfaces, and optical circuits.

We propose an alternative approach for obtaining struc-
tured metal layers involving glass poling and EFAD. The
scheme of the proposed process is presented in Fig. 1. The
first step is glass poling with a patterned anode [Fig. 1(a)]. In
the second step, the glass surface that was facing the anode
in the first step is coated with a metal layer [Fig. 1(b)]. The
final step is EFAD of the metal layer, applying non-patterned
electrodes [Fig. 1(c)]. A structured metal thin film is
obtained as a result of the completed process [Fig. 1(d)].

The depleted glass regions obtained by poling with a
patterned electrode (first step) behave as insulation regions,
and therefore, they prevent charge transfer. Although these
regions can be partially refilled by hydrogenated species,⁵
the mobility of these species is several orders of magnitudes
lower than that of alkali cations and the depleted regions do
not recover conductivity. As a consequence, metal ions from
the metal layer right above the depleted region cannot pass
into the glass matrix when potential is applied (third step).
As a result, these parts of the layer remain complete, i.e.,
conductive, while the layer parts right above the non-
depleted regions (i.e., the regions that were not in contact
with the patterned electrode during poling) dissolve.

A standard 1 mm thick microscope slide glass is used in
the experiment as the sample. The patterned anodic electrode
surface had different parts: (i) a 500 nm thick chromium

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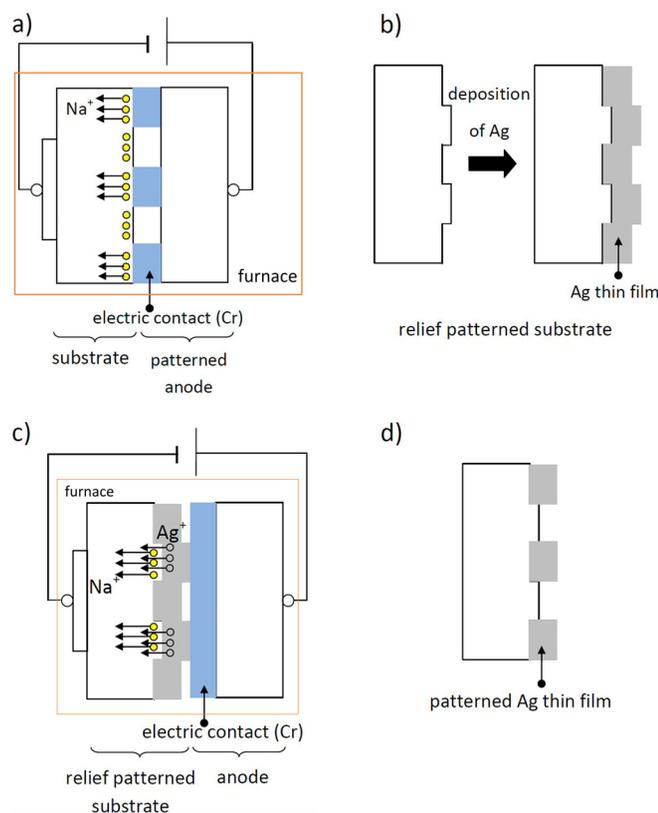


FIG. 1. Schematic presentation of the selective EFAD for structuring the metal layer: (a) poling of the glass substrate with a patterned anode. (b) Coating of the obtained relief structure with a thin metal film. (c) Application of a non-patterned anode to the metal film and selective dissolution of the film. (d) The final structured Ag thin film—the direct copy of the anode pattern in the metal layer.

92 layer, (ii) a part of the Cr layer etched into a pattern of
 93 25 μm wide chromium stripes separated by 10 μm wide and
 94 500 nm deep grooves having bare glass bottoms, and (iii) an
 95 uncoated part—bare BK7 substrate. A smooth aluminum plate
 96 was used as the cathode. Poling was performed in air at
 97 200 $^{\circ}\text{C}$, with an applied voltage of 900 V, for 2 h. After poling,
 98 a 70 nm thick silver layer was deposited onto the sample
 99 surface that was facing the anode during poling. Ag was
 100 deposited by electron beam evaporation onto a microscope
 101 slide without substrate pre-heating. After this, the sample
 102 was once more placed between the electrodes for EFAD.
 103 This time the anode was a non-patterned smooth chromium
 104 layer on BK7 [Fig. 1(c)]. The sample was treated in air at
 105 150 $^{\circ}\text{C}$, with an applied voltage of 300 V for 2 h. As a result
 106 of the selective EFAD process, a direct copy of the anode
 107 pattern was obtained in the conductive silver layer. Optical

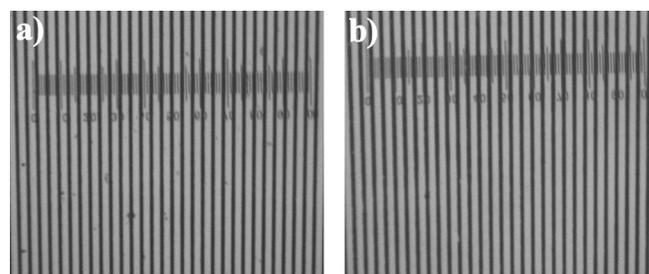


FIG. 2. Optical microscopy images of the (a) patterned anode and its (b) copy in the metal layer of the sample. The distance between lines on the rule is 10 μm .

108 microscopy images of the patterned anode and the sample
 109 are presented in Fig. 2. On this scale, it is not possible to dis-
 110 tinguish between the original pattern and the pattern obtained
 111 by selective EFAD of the deposited compact metal layer.

112 The bare substrate-like zone obtained on the sample is
 113 denoted as zone A. It corresponds to the bare BK7 substrate
 114 on the anode used in the first step. Figure 3(a) presents trans-
 115 mittance (T) measurements of zone A together with the data
 116 of an untreated microscopic glass. The part where the silver-
 117 like layer remained on the substrate is denoted as zone B. It
 118 corresponds to the part completely covered with chromium
 119 on the first anode. Figure 3(b) presents transmittance mea-
 120 surements of zone B together with the simulated transmittance
 121 of a silver layer, using optical constants from WVASE
 122 software. The correspondence of bare substrate data and
 123 zone A [Fig. 3(a)] and silver layer simulated data and zone B
 124 (presenting a typical metal behavior: low transmittance
 125 throughout visible and near-infrared part of the spectrum)
 126 [Fig. 3(b)] confirms that the anode pattern was copied onto a
 127 compact silver layer, resulting in compact metal and dielectric
 128 parts. Note that the non-compact metal film would show
 129 increased transmittance in the infrared part of the spectra
 130 since absorption would be primarily related to the surface
 131 plasmon resonance of isolated particles, as previously
 132 reported.¹¹

133 In order to get a better comparison of the patterned
 134 anode and its copy (Fig. 2), the samples were subject to
 135 SEM. It was found that Cr stripes of the anode are 10 μm
 136 wide with 25 μm separations and Ag stripes are 13 μm
 137 wide with 22 μm separations. SEM images (Fig. 4) illustrate
 138 the resemblance of the patterned anode [Fig. 4(a)] and its copy
 139 in the metal layer [Fig. 4(b)] on a smaller scale than the opti-
 140 cal microscopy ones (Fig. 2). Here, it is possible to clearly
 141 distinguish the differences between the two: the edges of Cr
 142 stripes are better defined than the Ag ones. By analyzing Ag

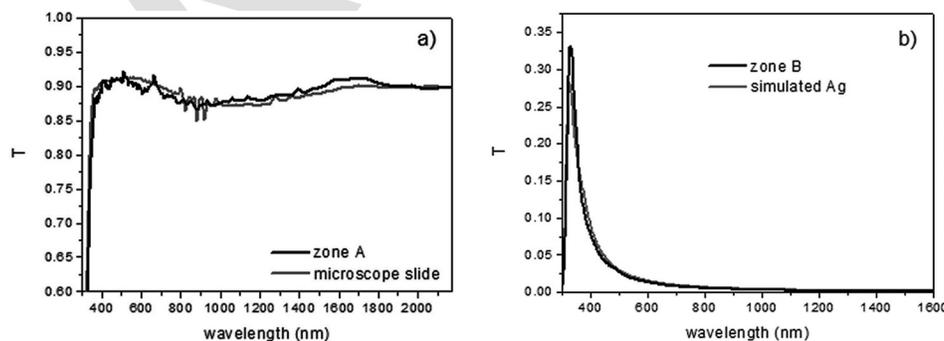


FIG. 3. Zone A (a) and zone B (b) transmittance measurements (black), together with the experimental data of the bare substrate (a) and the simulated transmittance of a 55 nm silver layer (b) (gray).

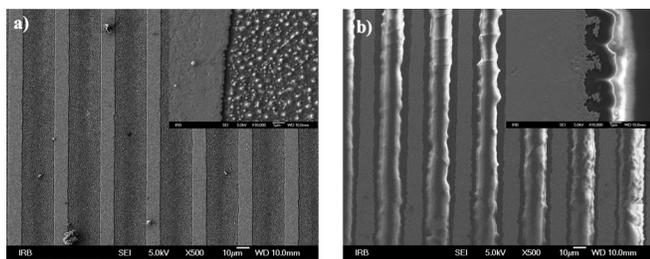


FIG. 4. SEM micrographs of the patterned anode (a) and its copy in the Ag layer (b). Metal stripes are uniformly light grey.

143 stripe edges (inset), it is possible to notice holes in the metal
 144 layer positioned within approx. $1.5 \mu\text{m}$ from the edge. The
 145 shapes and the holes of the edge irregularities, together with
 146 the holes on the stripe surface, suggest that the Ag dissolution
 147 process was not completed. Having in mind that the width of the
 148 area containing holes on the stripes surface is approx. $3 \mu\text{m}$ ($1.5 \mu\text{m}$
 149 from each edge) and that Ag stripes are approx. $3 \mu\text{m}$ wider than
 150 Cr stripes, it is possible to conclude that prolonged time of EFAD
 151 would result in completely dissolved Ag in edge areas containing
 152 holes, resulting in better defined stripes and a copy with a better
 153 resolution.

154
 155 The sample was investigated by atomic force microscopy (AFM)
 156 in order to check the profile of the final structure. The profile of
 157 the transition between the stripes is presented in Fig. 5. The
 158 lower part (zone A) corresponds to the bare substrate bottom
 159 obtained after selective dissolution of silver. The higher part
 160 (zone B) corresponds to the preserved compact metal stripes.
 161 The step height is around 45 nm , which is less than the thickness
 162 of the deposited silver layer (70 nm). One has to keep in mind
 163 that the coating was deposited onto the surface relief with a
 164 pattern consisting of glass grooves and glass tops. The depleted
 165 regions beneath the grooves of the poled glass surface were
 166 blocking EFAD, and so, the silver layer above the glass grooves
 167 was preserved. In this way, the metal stripes of the final surface
 168 relief pattern are formed at the positions of the former
 169 grooves. In other words, the metal layer is partially buried
 170 under the level of the final sample glass grooves. It has to be
 171 mentioned that as glass poling is taking place simultaneously
 172

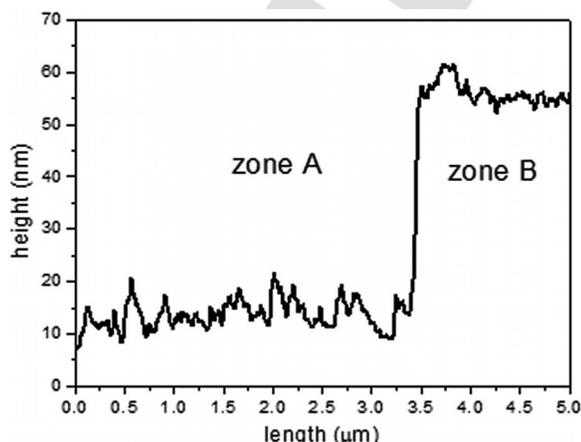


FIG. 5. AFM profile of the transition between the final pattern stripes: zone A corresponds to the bare substrate bottom (where silver was dissolved) and zone B to the compact silver layer.

with the EFAD process, it is to be expected that the glass
 tops obtained by poling were partially decreased during the
 subsequent EFAD. The result of all the applied processes is
 that the final relief corresponds to the one schematically pre-
 sented in Fig. 1(d), having 45 nm steps (Fig. 5).

The steepness of the ramp between the bare substrate
 and the silver stripe top is around 50%. This steepness
 depends on the ions' lateral drift, limiting the resolution⁵ that
 can be achieved by the proposed two-step process. Namely,
 the occurrence of the transition region around the edges of
 anode contacts due to the lateral drift of ions can be
 expected. Although lateral drifts cannot be avoided, it can be
 moderately controlled by the process conditions (potential,
 temperature, and duration of the process), the ions' concen-
 tration, and their kind. The lateral resolution of the fabricated
 structure will depend on the surface relief and alkali ion dis-
 tribution profile upon glass poling and EFAD of the metal
 layer. The resolution limit is yet to be determined through
 optimization of the mentioned process conditions. We expect
 that this technique is suitable to obtain structures of all the
 metals to which EFAD can be applied, such as noble^{6-8,11,13}
 and transition metals.¹⁴

In this work, it is demonstrated that the combination of
 glass poling and EFAD enables selective dissolution on con-
 ductive metal layers and that it can be used as a simple, alter-
 native method for micro- and nano-structuring of compact
 metal films. The main strength of the demonstrated techni-
 que is that it does not require a complex setup with expen-
 sive devices. Moreover, glass poling and EFAD processes
 use the same setup. Once a patterned anode for the first step
 is provided, a furnace together with a high voltage power
 supply and a device for metallization are sufficient. A prop-
 erly prepared patterned anode can be used tens of times.¹⁵ It
 must be emphasized that the processing time is independent
 of the size of the required patterned surface, in contrast to
 other structuring techniques. Indeed, the structuring process
 takes place simultaneously over the whole sample where the
 electric field is applied and the structured surface area is
 only limited by the electrode size. We expect that the use of
 EFAD as a selective process for structuring of metal thin
 films can contribute to broadening the production and gen-
 eral use of devices based on metal micro- and nano-
 structures.

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